AMENDMENTS TO THE CLAIMS

The following is a complete, marked up listing of revised claims with a status identifier in parentheses, underlined text indicating insertions, and strikethrough and/or double-bracketed text indicating deletions.

LISTING OF CLAIMS

1. (CURRENTLY AMENDED) An abrasive slurry composition for the chemical-mechanical polishing of a polysilicon layer formed over structures including silicon nitride comprising:

a carrier liquid;

abrasive particles; and

a non-ionic surfactant that selectively forms a passivation layer on exposed surfaces of the polysilicon layer wherein the non-ionic surfactant includes ethylene oxide-propylene oxide block copolymer alcohols selected from a group the group consisting of a first group of alcohols represented by the formula I

$$CH_3$$
- $(CH_2)_{\overline{n}}$ - $(CH(CH_3)CH_2O)_{\overline{y}}$ - $(CH_2CH_2O)_{\overline{x}}$ -OH (I)

wherein

n is an integer satisfying the relationship $3 \le n \le 22$;

y is an integer satisfying the relationship $1 \le y \le 30$; and

x is an integer satisfying the relationship $1 \le x \le 30$;

and a second group of alcohols represented by the formula II

$$R_2$$
— C_6H_4O — $(CH(CH_3)CH_2O)_y$ — $(CH_2CH_2O)_x$ — OH (II)

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wherein

 R_2 is $-C_9H_{19}$ or $-C_8H_{17}$.

2. (PREVIOUSLY PRESENTED) An abrasive slurry composition according to claim 1, further comprising:

a second surfactant, the second surfactant selectively forming a second passivation layer that will reduce a removal rate of silicon nitride or silicon oxide during the chemical-mechanical polishing.

3. (PREVIOUSLY PRESENTED) An abrasive slurry composition according to claim 1, wherein:

abrasive slurry includes a pH controller selected from the group consisting of KOH, NH₄OH, TMA, TMAH and TEA for maintaining a target slurry pH;

the target slurry pH is between about 7 and 12.

- 4. (CANCELED).
- 5. (CURRENTLY AMENDED) An abrasive slurry composition for the chemical-mechanical polishing of a polysilicon layer formed over structures including silicon nitride comprising:

a carrier liquid; abrasive particles; and a non-ionic surfactant that selectively forms a passivation layer on exposed surfaces of the polysilicon layer, including an ethylene oxide-propylene oxide block copolymer alcohol selected from a group consisting of alcohols represented by the formula I

$$CH_3$$
- $(CH_2)_{\overline{n}}$ - $(CH(CH_3)CH_2O)_{\overline{y}}$ - $(CH_2CH_2O)_{\overline{x}}$ -OH (I)

wherein

n is an integer satisfying the relationship $3 \le n \le 22$;

y is an integer satisfying the relationship $1 \le y \le 30$; and

x is an integer satisfying the relationship $1 \le x \le 30$;

an ethylene oxide-propylene oxide block copolymer alcohol selected from a group the group consisting of alcohols represented by the formula II

$$R_2$$
— C_6H_4O — $(CH(CH_3)CH_2O)_v$ — $(CH_2CH_2O)_x$ — OH (II)

wherein

$$R_2$$
 is $-C_9H_{19}$ or $-C_8H_{17}[[.]]$;

an ethylene oxide-propylene oxide-ethylene oxide tri-block polymer selected from a group the group consisting of polymers represented by the formula III

$$(CH_2CH_2O)_{\overline{z}}$$
 $(CH(CH_3)CH_2O)_{\overline{v}}$ $(CH_2CH_2O)_{\overline{x}}$ OH (III)

and a propylene oxide-ethylene oxide-propylene oxide tri-block polymer selected from a group the group consisting of polymers represented by the formula IV

$$(CH(CH_3)CH_2O)_{\overline{z}}$$
 $(CH_2CH_2O)_{\overline{v}}$ $(CH(CH_3)CH_2O)_{\overline{x}}$ OH (IV)

wherein

z is an integer satisfying the relationship $1 \le z \le 30$.

6. (PREVIOUSLY PRESENTED) An abrasive slurry composition according to claim 5, wherein:

z is an integer satisfying the relationship $5 \le z \le 30$. y is an integer satisfying the relationship $5 \le y \le 30$; and x is an integer satisfying the relationship $5 \le x \le 30$.

- 7. (ORIGINAL) An abrasive slurry composition according to claim 6, wherein: the relationship $20 \le z + y + x \le 70$ is satisfied.
- 8. (PREVIOUSLY PRESENTED) An abrasive slurry composition according to claim 5, wherein:

z is an integer satisfying the relationship $10 \le z \le 30$. y is an integer satisfying the relationship $10 \le y \le 30$; and x is an integer satisfying the relationship $10 \le x \le 30$.

9. (ORIGINAL) An abrasive slurry composition according to claim 5, wherein: the abrasive particles are silica, have an average size of less than about 1 μ m and are about 5 to 30 wt% of the slurry composition;

the target slurry pH is between about 8 and 12; and the non-ionic surfactant is at least 0.001 wt% of the abrasive slurry composition.

10. (ORIGINAL) An abrasive slurry composition according to claim 5, wherein:

the abrasive particles are silica, have an average size of less than about 100 nm and are about 10 to 20 wt% of the slurry composition;

the target slurry pH is between about 10 and 11; and the non-ionic surfactant is between about 0.005 and 0.1 wt% of the abrasive slurry composition.

11. (ORIGINAL) An abrasive slurry composition according to claim 2, wherein: the abrasive particles are silica, have an average size of less than about 1 μ m and are about 5 to 30 wt% of the slurry composition;

the target slurry pH is between about 7 and 12;

the non-ionic surfactant is at least about $0.001~\rm wt\%$ of the abrasive slurry composition; and

the second surfactant includes an imine or amine compound and is between about 0.001 and 10 wt% of the abrasive slurry composition.

12-13. (CANCELED)

14. (PREVIOUSLY PRESENTED) An abrasive slurry composition for the chemical-mechanical polishing of a polysilicon layer formed over structures including silicon nitride comprising:

a carrier liquid;

abrasive particles; and

a non-ionic surfactant that selectively forms a passivation layer on exposed surfaces of the polysilicon layer, wherein the non-ionic surfactant includes at least one surfactant selected from the group consisting of

ethylene oxide-propylene oxide block copolymer alcohols represented by the formula I

$$CH_3^-(CH_2)_n^-(CH(CH_3)CH_2O)_v^-(CH_2CH_2O)_x^-OH$$
 (I);

ethylene oxide-propylene oxide block copolymer aryl alcohols represented by the formula II

$$R_2$$
— C_6H_4O — $(CH(CH_3)CH_2O)_v$ — $(CH_2CH_2O)_x$ — OH (II)

wherein

$$R_2$$
 is $-C_9H_{19}$ or $-C_8H_{17}$;

and the non-ionic surfactant includes at least one surfactant selected from the group consisting of ethylene oxide-propylene oxide-ethylene oxide tri-block polymers represented by the formula III

$$(CH_2CH_2O)_{\overline{z}}$$
 $(CH(CH_3)CH_2O)_{\overline{y}}$ $(CH_2CH_2O)_{\overline{x}}$ OH (III);

and

propylene oxide-ethylene oxide-propylene oxide tri-block polymers represented by the formula IV

$$(CH(CH_3)CH_2O)_{\overline{z}}$$
 $(CH_2CH_2O)_{\overline{y}}$ $(CH(CH_3)CH_2O)_{\overline{x}}$ OH $(IV);$

wherein

n is an integer satisfying the relationship $3 \le n \le 22$;

z is an integer satisfying the relationship $1 \le z \le 30$

y is an integer satisfying the relationship $1 \le y \le 30$; and

x is an integer satisfying the relationship $1 \le x \le 30$.

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15. (PREVIOUSLY PRESENTED) An abrasive slurry composition according to claim 14, wherein:

z is an integer satisfying the relationship $5 \le z \le 30$. y is an integer satisfying the relationship $5 \le y \le 30$; and x is an integer satisfying the relationship $5 \le x \le 30$.

- 16. (ORIGINAL) An abrasive slurry composition according to claim 14, wherein: the relationship $20 \le z + y + x \le 70$ is satisfied.
- 17. (PREVIOUSLY PRESENTED) An abrasive slurry composition according to claim 14, wherein:

z is an integer satisfying the relationship $10 \le z \le 30$. y is an integer satisfying the relationship $10 \le y \le 30$; and x is an integer satisfying the relationship $10 \le x \le 30$.

18-27. (CANCELED)

28. (PREVIOUSLY PRESENTED) An abrasive slurry composition for the chemical-mechanical polishing of a polysilicon layer formed over structures including silicon nitride comprising:

a carrier liquid; abrasive particles; and a non-ionic surfactant that selectively forms a passivation layer on exposed surfaces of the polysilicon layer, wherein

the non-ionic surfactant includes at least one surfactant selected from at least three of the four groups of alcohols consisting of a first group consisting of ethylene oxide-propylene oxide block copolymer alcohols represented by the formula I

$$CH_3$$
- $(CH_2)_n$ - $(CH(CH_3)CH_2O)_v$ - $(CH_2CH_2O)_x$ - OH (I);

a second group of ethylene oxide-propylene oxide block copolymer aryl alcohols represented by the formula II

$$R_2$$
— C_6H_4O — $(CH(CH_3)CH_2O)_v$ — $(CH_2CH_2O)_x$ — OH (II)

wherein

$$R_2$$
 is $-C_9H_{19}$ or $-C_8H_{17}$;

a third group of ethylene oxide-propylene oxide-ethylene oxide tri-block polymer alcohols represented by the formula III

$$(CH_2CH_2O)_{\overline{z}}$$
 $(CH(CH_3)CH_2O)_{\overline{y}}$ $(CH_2CH_2O)_{\overline{x}}$ OH (III);

and

a fourth group of propylene oxide-ethylene oxide-propylene oxide tri-block polymer alcohols represented by the formula IV

$$(CH(CH_3)CH_2O)_{\overline{z}}$$
 $(CH_2CH_2O)_{\overline{y}}$ $(CH(CH_3)CH_2O)_{\overline{x}}$ OH (IV);

wherein

n is an integer satisfying the relationship $3 \le n \le 22$;

z is an integer satisfying the relationship $1 \le z \le 30$

y is an integer satisfying the relationship $1 \le y \le 30$; and

x is an integer satisfying the relationship $1 \le x \le 30$.

29. (PREVIOUSLY PRESENTED) An abrasive slurry composition according to claim 28, wherein:

z is an integer satisfying the relationship $5 \le z \le 30$. y is an integer satisfying the relationship $5 \le y \le 30$; and x is an integer satisfying the relationship $5 \le x \le 30$.

- 30. (ORIGINAL) An abrasive slurry composition according to claim 28, wherein: the relationship $20 \le z + y + x \le 70$ is satisfied.
- 31. (PREVIOUSLY PRESENTED) An abrasive slurry composition according to claim 28, wherein:

z is an integer satisfying the relationship $10 \le z \le 30$. y is an integer satisfying the relationship $10 \le y \le 30$; and x is an integer satisfying the relationship $10 \le x \le 30$.

32-38. (CANCELED)

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